

Hybrid Approach to Conduct Failure Prognostics of Automotive Electronic Control Unit Using Stress Sensor as *In Situ* Load Counter

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Abstract—A model/sensor hybrid approach is implemented to conduct failure prognostics of an automotive electronic control unit (ECU). A 3-D finite-element model simulating a complex ECU is built, and its predictability is calibrated and verified by an optical displacement measurement technique called moiré interferometry. On the sensor front, a silicon-based piezoresistive stress sensor is embedded into the ECU to provide *in situ* stress measurements during operations. A stress metric is defined using the stress values of 12 cells in each sensor, and it is converted to *in situ* loading histories using the calibrated finite-element model. The modeling and verification steps that lead to the predictive finite-element model are described. The proposed hybrid approach is implemented using the data obtained from a molded ECU subjected to thermal cycling conditions, and the forces at an interface between an aluminum wire bond and metal pad are investigated.

Index Terms—Electronic control unit (ECU), finite-element analysis (FEA) modeling, load counter, model verification, moiré interferometry, stress sensor.

I. INTRODUCTION

IT IS expected that advanced electronic components and smart systems would dictate the level of innovations in nearly all industrial sectors, including automotive and other transport/logistics solutions, production equipment, and energy and other infrastructure. In particular, more and more advanced electronics have been adopted in automotive technologies to enhance user interfaces.

One such component is an automotive electronic control unit (ECU), which is an embedded system that controls an electrical system or subsystems in a transport vehicle. Typical applications include engine control, power control, and transmission control. ECU performance is directly related to: 1) on-road performance; 2) fuel consumption; 3) exhaust gas reduction; and 4) extended battery life. Connectivity and

automation for autonomous vehicle technology will require significant changes in existing ECU technologies.

In a conventional ECU, a protective metal case has been used to ensure reliability under harsh environmental conditions. Recently, an epoxy molding compound (EMC) was adopted to replace the metal case. The EMC technology reduced the manufacturing cost significantly, yet the presence of a large amount of outer EMC increased the stresses of ECUs during the transfer molding process and operations [1]–[3]. Reliability of ECU is directly related to automobile safety. The long-term reliability of this newly adopted manufacturing technology should be assessed to make the technology a more viable alternative to various ECUs.

A piezoresistive stress sensor was developed to measure directly the stresses of a silicon chip embedded in a package. The sensor was implemented successfully to investigate the effect of encapsulation process on the package stress [4] and to monitor the wire-bonding process [5]. The sensor was also considered for prognostics and health management [6]. In [6], the changes in stresses measured by the sensor were observed before delamination occurred, which could be used as a signal for failure.

Numerical modeling such as finite-element analysis (FEA) can be calibrated and subsequently utilized to predict the thermally induced deformations of the critical parts in molded ECUs. However, accurate assessment of the deformations under automotive driving conditions is challenging because the operating environments of ECU vary significantly with users and locations. It is important to document the *in situ* loading condition to conduct failure prognostics realistically. The piezoresistive stress sensor has a unique advantage over other deformation measurement techniques; it can provide *in situ* stress measurements during operations. This advantage can be further utilized to count actual loading conditions.

In this paper, a 3-D finite-element model simulating a complex ECU is built, and its predictability is examined and calibrated by an optical displacement measurement technique called moiré interferometry. The calibrated model and the load count obtained from the stress sensor provide a hybrid approach to conduct failure prognostics of molded ECUs. The modeling construction and a detailed procedure to calibrate the model are presented after briefly describing two experimental techniques. Then, the proposed hybrid approach is presented

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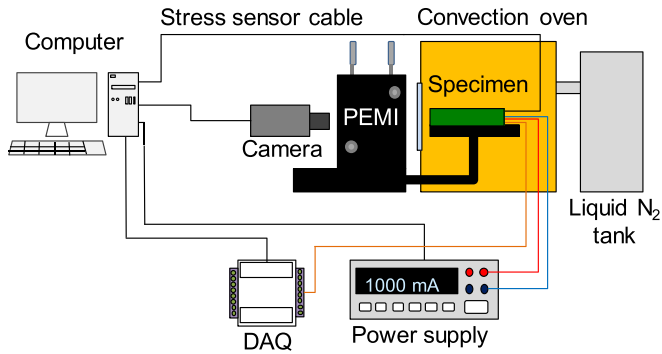


Fig. 1. Schematic of the experimental system for displacement measurements.

using the data obtained from the molded ECUs subjected to thermal cycling conditions.

II. BACKGROUND: EXPERIMENTAL TECHNIQUES

A. Moiré Interferometry

Moiré interferometry maps the deformations of advanced engineering structures with extremely high resolution. It has been used extensively for the thermal deformation analyses of various semiconductor packages [7]–[15]. In this method, a high-frequency cross-line grating is replicated on a specimen cross section, and it deforms together with the specimen. A pair of collimated beams of laser light strikes the specimen and a portion is diffracted back, perpendicular to the specimen cross section. They interfere to produce moiré fringe patterns, representing the contour map of U or V displacement fields on the specimen grating. At each (x, y) point on the fringe pattern, the displacement can be calculated by [9]

$$U(x, y) = \frac{1}{2f_s} N_x(x, y) \quad V(x, y) = \frac{1}{2f_s} N_y(x, y) \quad (1)$$

where N is the fringe order and f_s is the frequency of the specimen grating. In routine practice of moiré interferometry, $f_s = 1200$ lines/mm, which produces a contour interval of 417 nm per fringe order.

The real-time moiré interferometry setup described in [12] and [14] was used to document the thermal deformations of ECUs. A complete experimental setup is illustrated in Fig. 1. The major components in the setup include a portable engineering moiré interferometer and a computer-controlled environmental chamber. The required passive and active thermal loadings are provided by the convection oven, liquid nitrogen, and a power supply. A data acquisition (DAQ) hardware is used to record the temperatures of various locations of the specimen during experiments. With the setup, the in-plane deformations of ECUs can be documented as a function of temperature.

B. Silicon-Based Piezoresistive Stress Sensor

The sensor used in this paper is a complementary metal–oxide–semiconductor-based piezoresistive stress sensor [16]. Sensing elements are created by the channels of metal–oxide–semiconductor field-effect transistors (MOSFETs) in a current

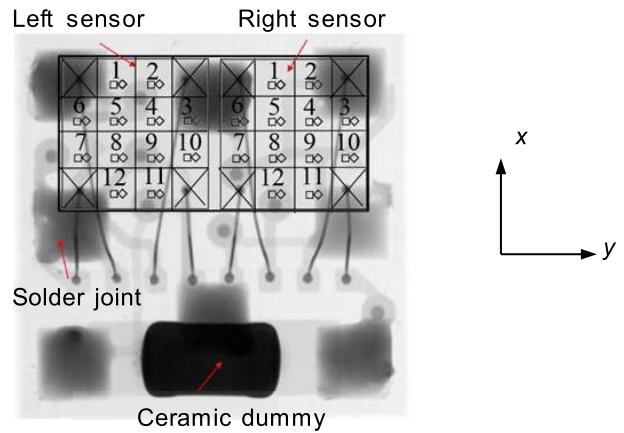


Fig. 2. X-ray image of LGA sensor package.

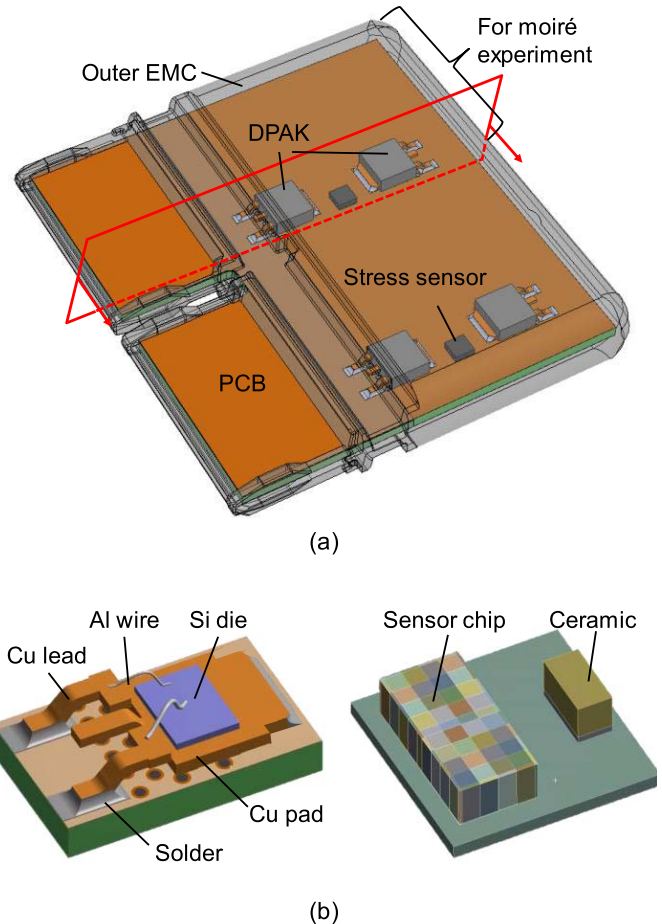


Fig. 3. Schematic illustration of (a) ECU test vehicle. (b) Internal details of the DPAK and the stress sensor.

mirror circuit on a silicon substrate [17]. The stress-sensitive channels of MOSFET in both branches of current mirrors are oriented differently with respect to the crystallographic axes of silicon, which makes the transistors respond differently to applied mechanical stresses. As a result, the circuit becomes out of balance under any mechanical stresses. This effect is quantified by measuring current differences in the two branches of the current mirror.

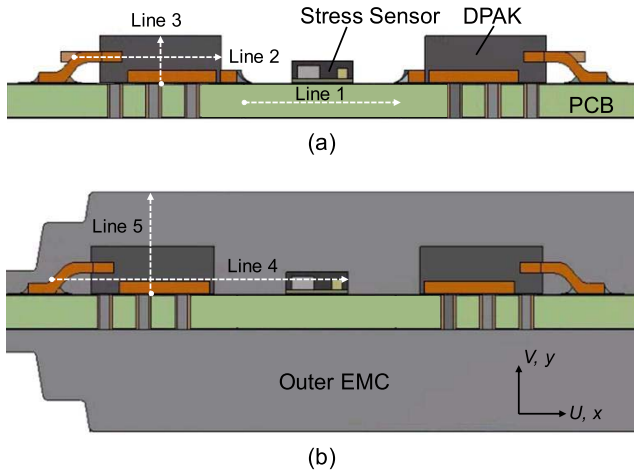


Fig. 4. Cross sections of moiré specimens (a) without and (b) with outer EMCs.

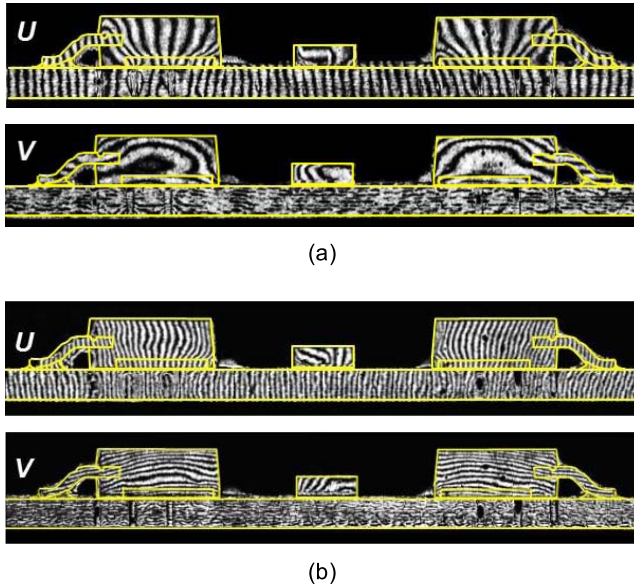


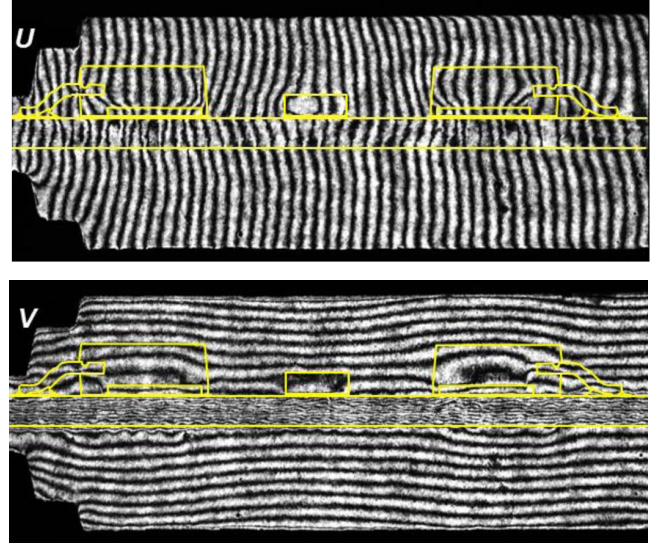
Fig. 5. Fringe patterns of unmolded ECU (a) at $-40\text{ }^{\circ}\text{C}$ and (b) at $125\text{ }^{\circ}\text{C}$.

In this paper, the p-channel metal–oxide–semiconductor (pMOS) current mirror with two channels in the directions of 0° and 90° is used for measurement of the in-plane normal stress difference. The applied stresses are determined from the measured current differences by

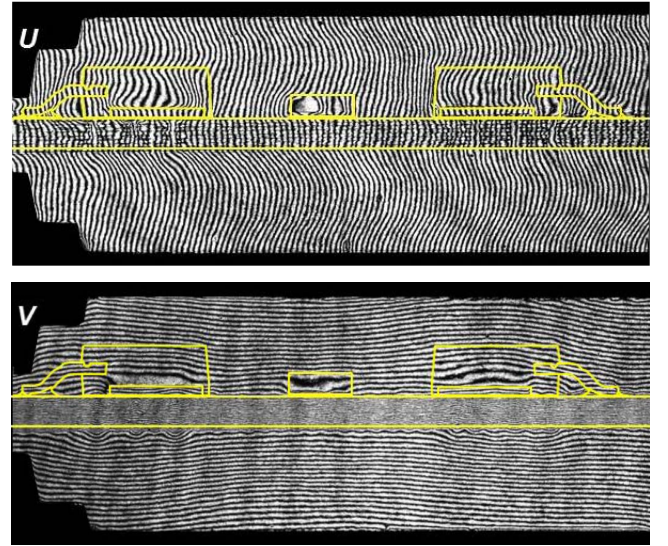
$$\sigma = \sigma_{xx} - \sigma_{yy} \approx -\frac{2}{\Pi_D^p(T)} \frac{I_{D|0^{\circ}} - I_{D|90^{\circ}}}{I_{D|0^{\circ}} + I_{D|90^{\circ}}} \quad (2)$$

where $\Pi_D^p(T)$ are the temperature-dependent effective piezoresistive constants that are influenced by the current mirror circuit for pMOS, I_D is the drain current of the current mirrors, and the subscripts indicate the directions of the channels.

The construction of the sensor used in this paper is shown in Fig. 2. The silicon chip consists of two stress sensors, and it is packaged in a standard land grid array (LGA) package [17]. Each stress sensor has 12 measurement cells, placed in 4×4 matrix (cells in the corners are inactive, left for bonding pads) [18].



(a)



(b)

Fig. 6. Fringe patterns of molded ECU (a) at $-40\text{ }^{\circ}\text{C}$ and (b) at $125\text{ }^{\circ}\text{C}$.

III. CALIBRATION AND VALIDATION OF NUMERICAL MODEL

A. Test Vehicle

A test vehicle used in this paper is shown schematically in Fig. 3(a). Two pairs of discrete packaging (DPAK) are mounted on a printed circuit board (PCB), and two stress sensors are mounted on the middle of each DPAK pair. The internal details of the DPAK and the stress sensor are shown in Fig. 3(b). The ECU was molded by an EMC through a transfer molding process. Two different specimens were used for displacement measurements: unmolded ECU (without outer EMC) and molded ECU (with outer EMC).

B. Displacement Measurements by Moiré Interferometry

The specimens were cut and ground flat to expose desired cross sections [see the red lines in Fig. 3(a)]. The cross sections

TABLE I
MATERIAL PROPERTIES OF NONPOLYMER MATERIALS

Material	Young's modulus [GPa]	Poisson's Ratio	CTE [ppm/°C]
Silicon die	x: 168.9 y: 168.9 z: 130.2	xy: 0.064 yz: 0.361 xz: 0.361	2.8
Copper in DPAK	125	0.34	17
Copper in PCB	80	0.34	17
Solder	49.55	0.36	20
Al wire	64	0.33	25.3
Ceramic	107	0.25	5

TABLE II
MATERIAL PROPERTIES OF POLYMER MATERIALS

Material	CTE [ppm/°C] below T_g	CTE [ppm/°C] above T_g	T_g [°C]
PCB prepreg	x: 14	x: 40	149
	y: 16	y: 40	
	z: 52	z: 247	
Outer EMC	12	25	110
DPAK mold	12	40	100
Sensor mold	8.2	26.7	106

of moiré specimens are shown in Fig. 4, where the DPAKs and the stress sensor are exposed on the cross sections. The cross-line diffraction gratings ($f_s = 1200$ lines/mm) were replicated on the cross sections.

The specimens were placed inside the convection oven, and the deformations were documented as a function of temperature from -40 °C to 125 °C. Fringe patterns recorded at -40 °C and 125 °C are shown in Figs. 5 and 6 for the package without and with outer mold, respectively, where the DPAK packages, the stress sensor, and the PCB were outlined directly on the fringe patterns. The displacement fields clearly show the complex nature of thermal deformations. It is worth noting that the deformations of DPAK packages in Fig. 6 are completely different from those in Fig. 5; it is attributed to the constraints from the outer EMC.

C. Model Calibration

Detailed 3-D models with dimensions identical to the moiré specimens were constructed for model calibration. The material properties used in the numerical analysis are summarized in Tables I and II. A traction-free boundary condition was imposed on the cross sections to simulate the moiré experiments. The stress-free temperature was room temperature (22 °C), where the specimen grating was replicated. The same passive thermal loading used in the moiré experiment was applied to the models.

Representative displacement fields obtained at -40 °C are shown in Fig. 7 where the postprocessing produces the displacement fields with the same contour interval as the moiré fringes (417 nm). Quantitative comparisons between the modeling predictions and the moiré results are made in Figs. 8 and 9 for the unmolded and molded packages,

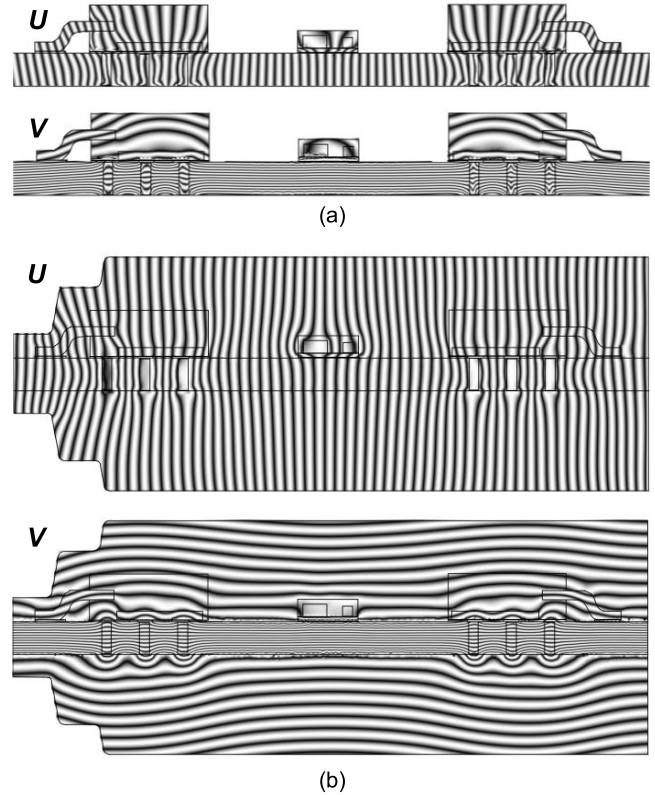


Fig. 7. Displacement fields at -40 °C obtained by FEA. (a) Unmolded ECU. (b) Molded ECU. The postprocessing produces the displacement fields with the same contour interval as the moiré fringes (417 nm).

respectively. The displacements were extracted from the fringe patterns in Figs. 5 and 6 first along the lines shown in Fig. 4. Then, the experimental results are compared with the initial modeling results in Figs. 8 and 9, which appear in the plots as “before calibration.” The initial modeling predicted the deformation of PCB reasonably well, but a large discrepancy was observed in the DPAK and the outer EMC.

The outer EMC and DPAK mold occupy the majority of volume inside ECUs. They were calibrated to represent the effective properties that mimic the real behavior of the materials. A supplementary sensitivity study indicated that the deformation field was most sensitive to the coefficient of thermal expansion (CTE). The CTE values of these two materials were adjusted continuously until the discrepancy

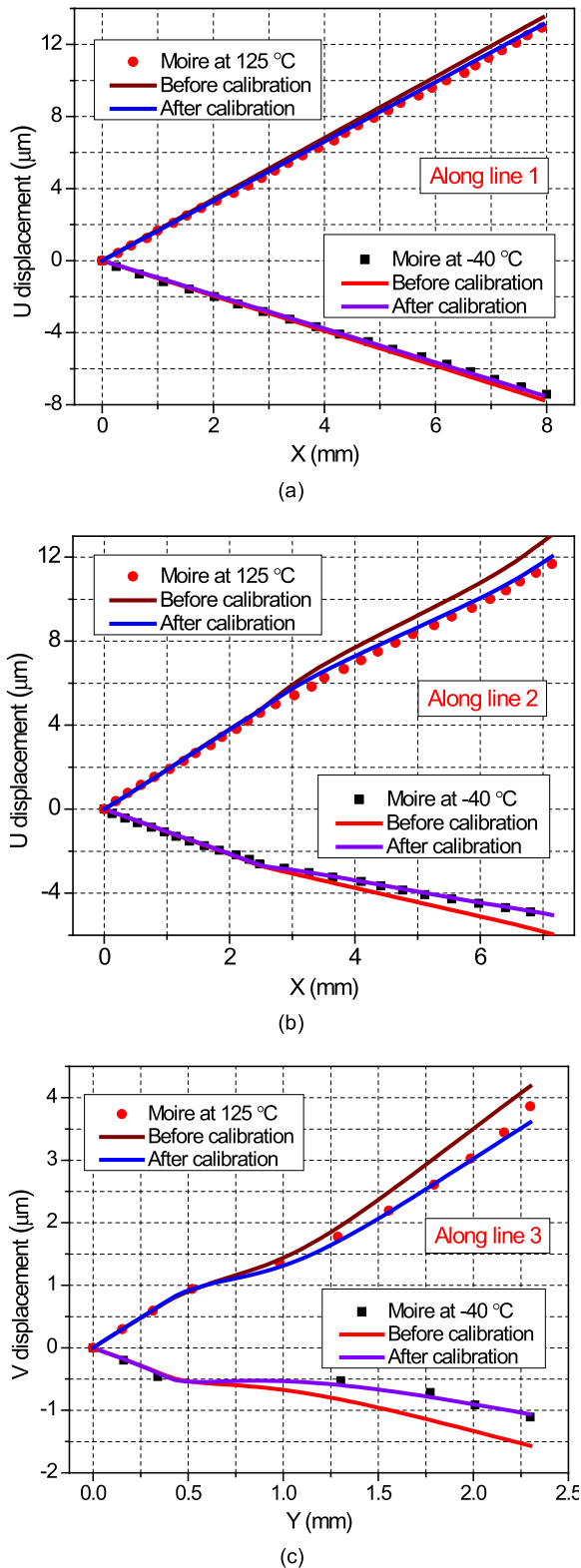


Fig. 8. Numerical predictions of the unmolded package subjected to a passive thermal loading condition are compared with experimental data shown in Fig. 5. (a) U along line 1 (PCB). (b) U along line 2 (DPAK). (c) V along line 3 (DPAK).

between numerical and experimental results became minimal. The CTE of the DPAK mold was calibrated first using experimental data of the unmolded ECU. The CTE of the outer EMC was subsequently calibrated using experimental data of

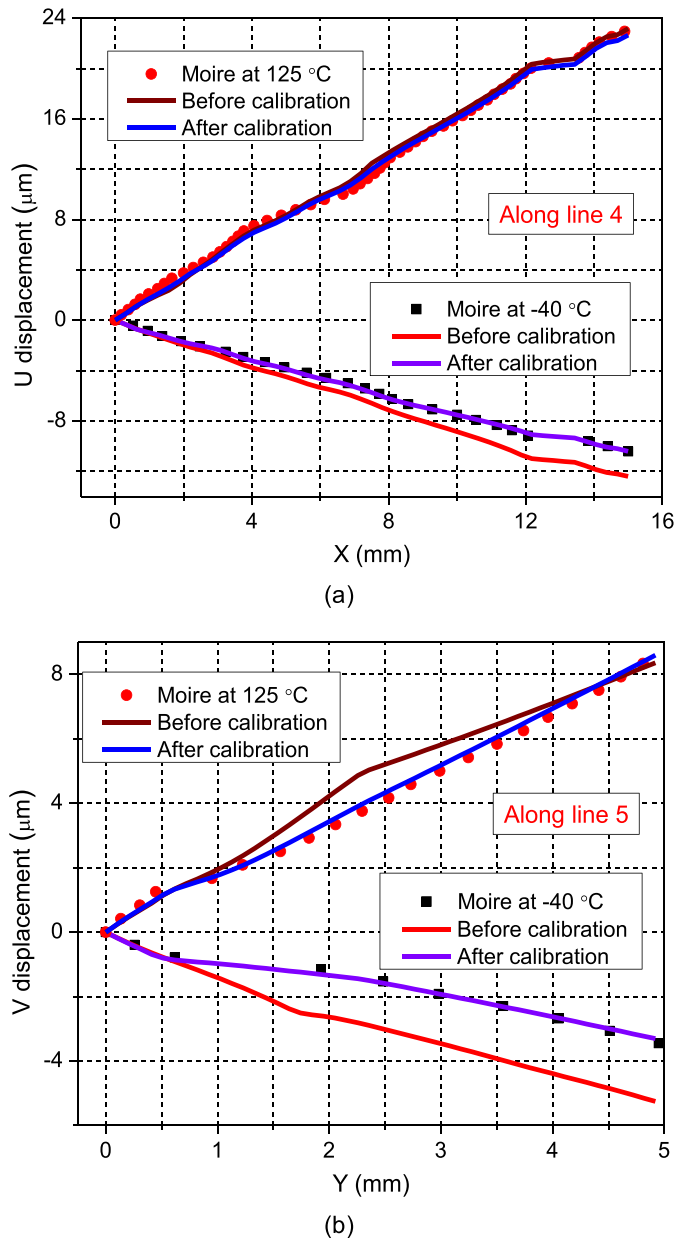


Fig. 9. Numerical predictions of the molded package subjected to a passive thermal loading condition are compared with experimental data shown in Fig. 6. (a) U along line 4. (b) V along line 5.

the molded ECU. The comparisons after calibration are also shown in Figs. 8 and 9 (“after calibration”). It is evident that the calibrated model can predict the displacement fields accurately.

D. Validation of Calibrated Model

A set of experiments under active thermal loading was conducted to verify the validity of the calibrated model. The specimen configuration had to be modified to utilize the DPAK power packages for active loading. The modification is shown in Fig. 10, where the power packages were placed slightly away from the stress sensor so that they were not damaged when the stress sensor was exposed to the cross section for moiré experiments.

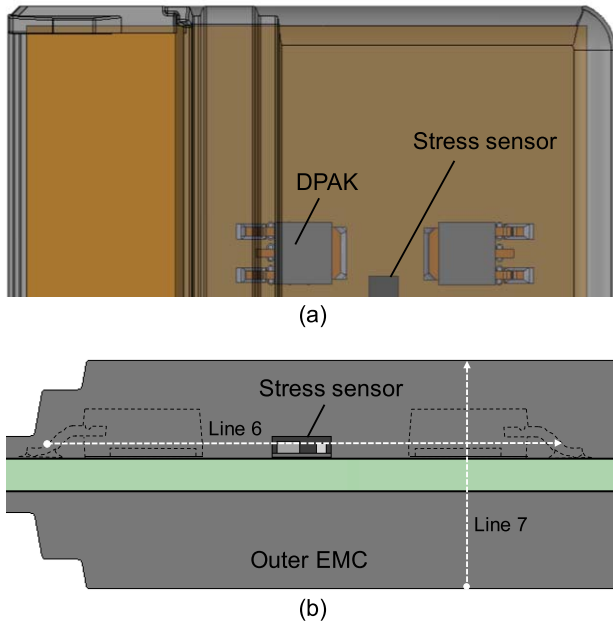


Fig. 10. Molded ECU specimen used for moiré experiments under active thermal loading. (a) Top view. (b) Front view.

Both DPAK packages were loaded by an electrical power of 1.2 W at room temperature (22 °C). The fringe patterns were recorded during the active loading. Representative fringe patterns obtained during the transient period are shown in Fig. 11(a), which were recorded at 260 s after DPAK packages were powered up. The fringe patterns in Fig. 11(b) were recorded at the thermal steady-state condition, which was obtained around 30 min after the power cycling started.

A thermal simulation was first conducted to obtain the temperature distribution at the steady-state condition. The surface temperatures at various locations at the steady-state condition were measured using thermocouples, and they were compared with the numerical predictions. The results are shown in Fig. 12, which corroborates the accuracy of the temperature prediction within ± 3 °C.

The temperature distribution obtained from the thermal modeling was loaded to the calibrated structural model, and the deformation at the steady-state condition was calculated. The displacements were extracted along lines 6 and 7 [Fig. 10(b)] from the fringe patterns shown in Fig. 11(b), and they are compared with the numerical predictions in Fig. 13. The good correlations confirm the accuracy of the calibrated model.

IV. IMPLEMENTATION FOR FAILURE PROGNOSTICS

Several failure modes are known in the DPAK inside an ECU. They include delamination between molding compound and copper lead frame, wire bond failure, and solder joint failure [19]. Traditionally, the most dominant failure in the power electronic device happens at the bond wires and one of the most common failure modes is wire lift-off [20]–[22]. Fig. 14(a) shows an example of the interfacial delamination between the gate Al wire and Cu lead inside a molded ECU after a series of thermal cycling tests [2]. The interface between an aluminum wire bond and metal pad shown

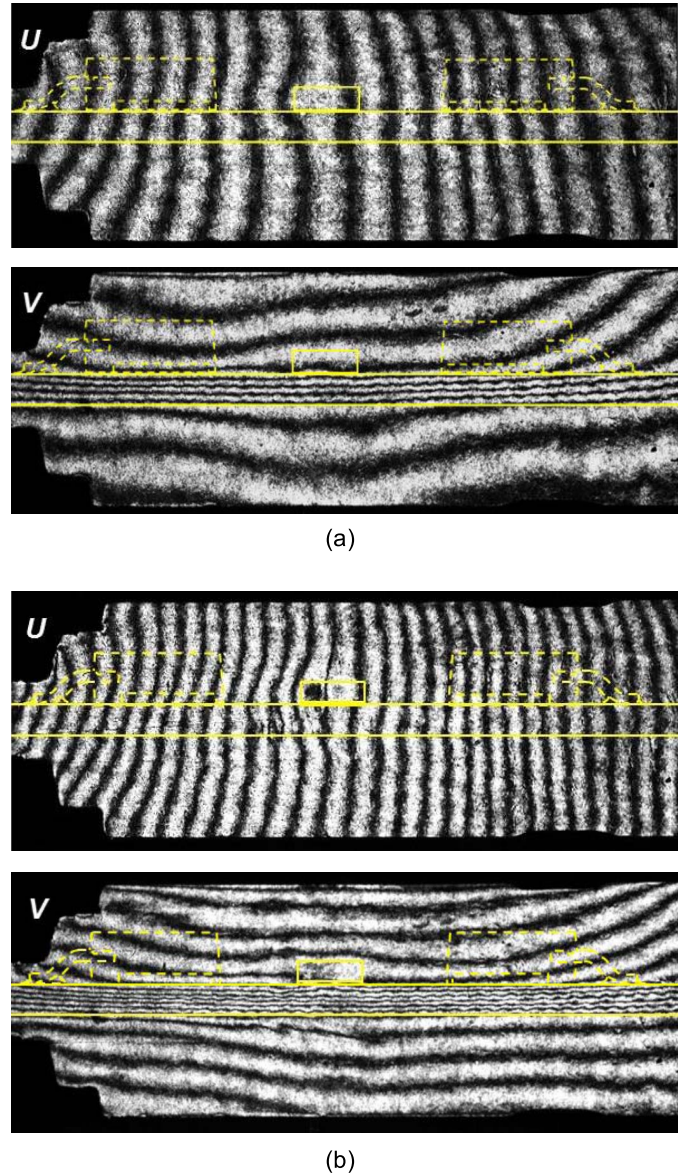


Fig. 11. Fringe patterns obtained (a) at 260 s after DPAK packages are powered up and (b) after the steady-state condition is reached.

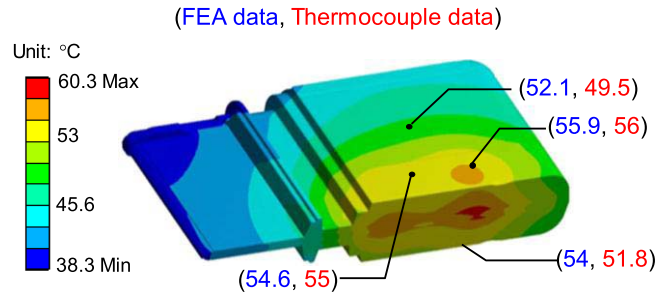
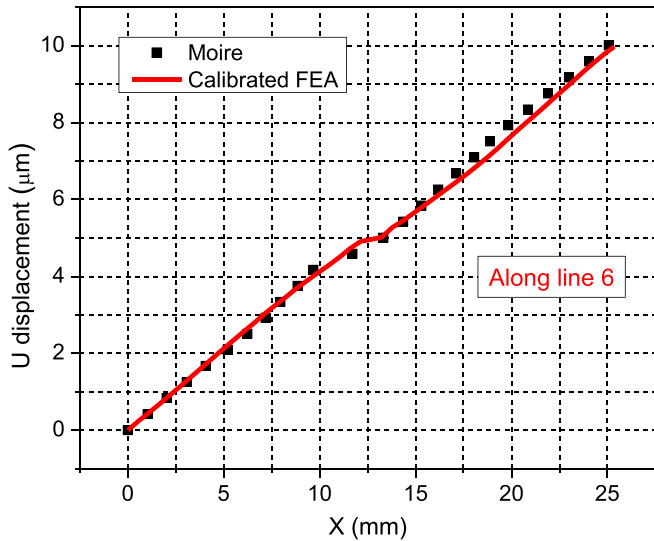


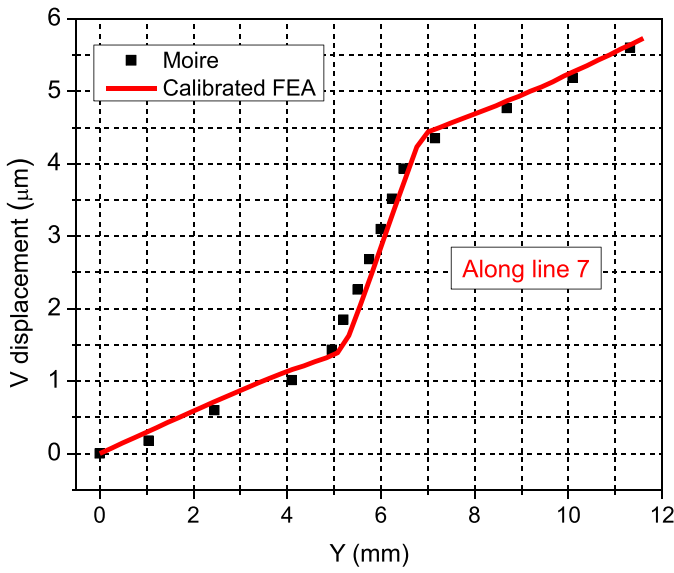
Fig. 12. Temperature distribution inside ECU at steady state.

in Fig. 14(b) is selected for the failure prognostics analysis in this paper.

A passive thermal cycling test is used to present the proposed method. The stress sensor is first used to count the actual operating conditions of five ECUs. Then, the calibrated FEA modeling is utilized to determine the thermally induced stresses of the wire bond of each unit.



(a)



(b)

Fig. 13. Numerical predictions of the molded package subjected to an active thermal loading condition are compared with experimental data shown in Fig. 11. (a) U along line 6. (b) V along line 7.

A. Stress Prediction Using Calibrated Model

The calibrated FEA model of the molded ECU package used in the analysis is shown in Fig. 15(a), where the location of the stress sensor is marked by a red circle. Special considerations were given for the stress sensor cells. As can be seen from Fig. 15(b), the sensor was discretized to produce a 10- μ m-thick top layer, which was equal to the thickness of the MOSFET branch in the stress sensor. In addition, each stress-sensing cell was divided into a 4×4 matrix of elements. Only the elements occupying the stress-sensitive current mirrors were used for stress calculations.

The FEA modeling was conducted to simulate the passive thermal loading of -40 °C– 125 °C; the stress-free temperature was room temperature. The in-plane normal stress difference ($\sigma_{xx} - \sigma_{yy}$) was calculated from the elements representing the stress-sensing cells. The results at

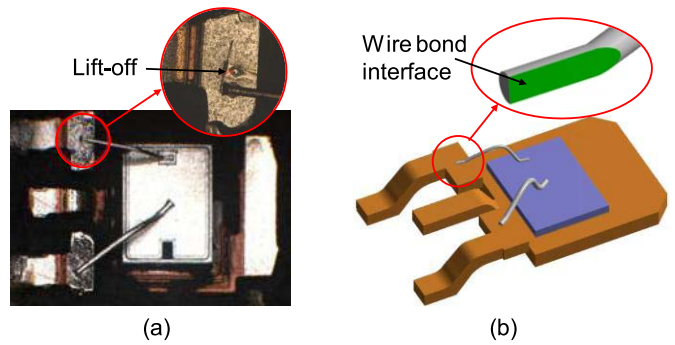
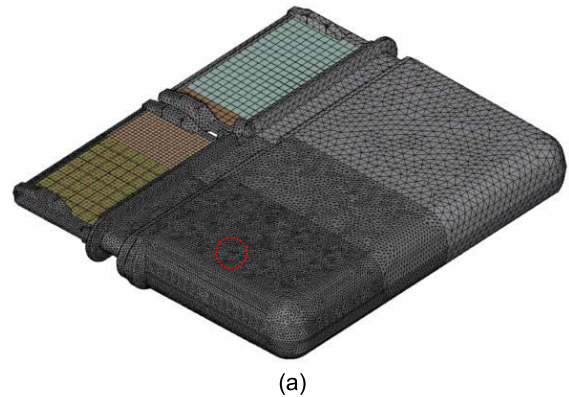
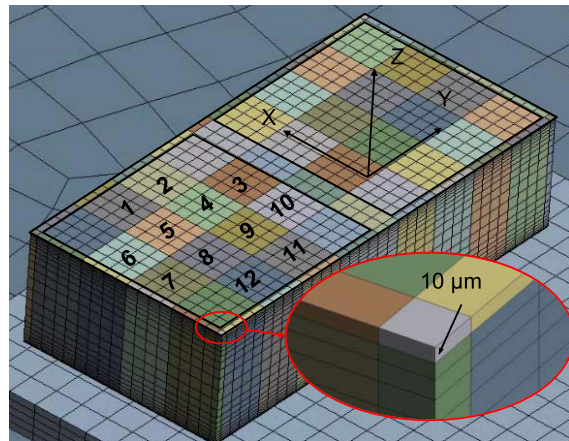


Fig. 14. (a) Wire bond “lift-off” failure in a DPAK. (b) Al wire bond interface of interest.



(a)

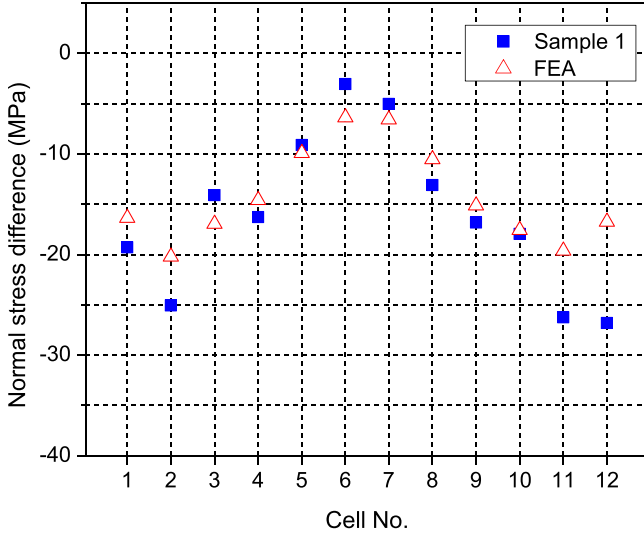


(b)

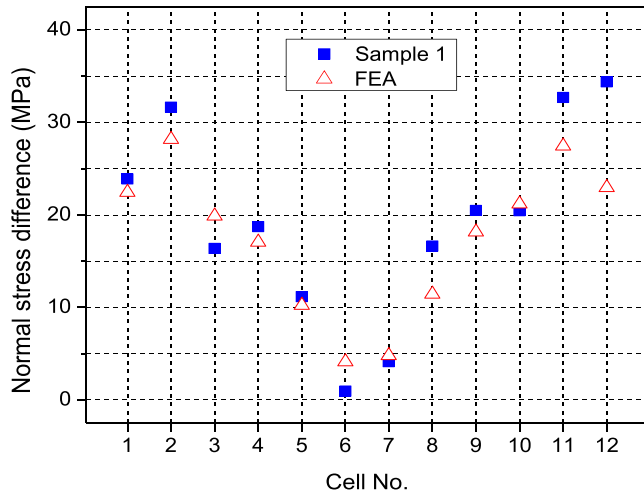
Fig. 15. FEA models of (a) whole ECU and (b) stress sensor.

-40 °C and 125 °C are plotted in Fig. 16(a) and (b), respectively.

The in-plane normal stress differences measured from an ECU that was subjected to the same thermal excursion are also plotted in Fig. 16. It is noted that the values were obtained by subtracting the stress signals at room temperature from those measured at -40 °C and 125 °C, which represented the in-plane normal stress differences caused by cooling or heating the unit to the two temperatures from room temperature. The comparison clearly indicates that the in-plane normal stress difference of each cell can be predicted by the calibrated FEA model quantitatively.



(a)



(b)

Fig. 16. Stress signals of an ECU is compared with the results obtained from FEA prediction (a) at $-40\text{ }^{\circ}\text{C}$ and (b) at $125\text{ }^{\circ}\text{C}$.

B. Stress Sensor as a Load Counter

The operating conditions of automotive vary significantly from locations to locations. The sensor can monitor the stress continuously, and it can be used to record the actual conditions under which an ECU is being operated (i.e., a load counter). The thermal cycling test and the calibrated model are employed to illustrate the load-counter concept.

A load-counter metric can be defined conceptually using the stress signals from all 12 cells as

$$\sigma^*(l) = \sum_{j=1}^{12} \sigma_j(l) = L(l) \quad (3)$$

where σ^* is a load-counter metric, σ_j is the value of in-plane normal stress difference from the j th cell, L is a load-counter function, and l is a load-counter variable that represents the *in situ* loading condition such as thermal loading,

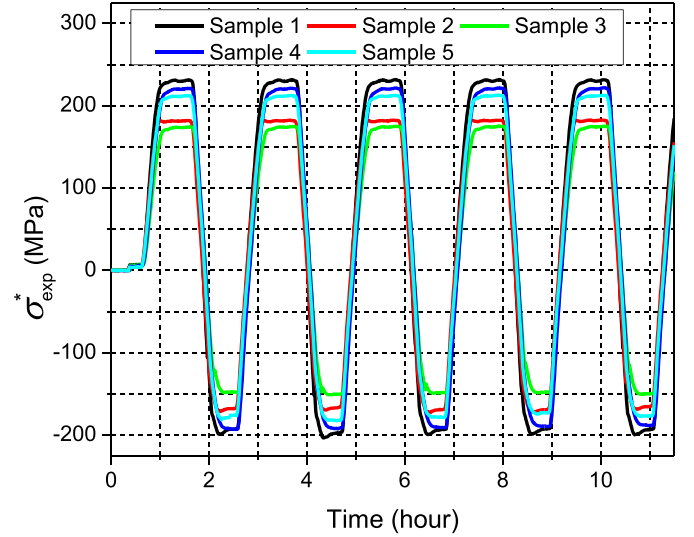


Fig. 17. Load-counter metric during the first five thermal cycles.

mechanical loading, and impact loading. The load-counter function can be obtained using the calibrated model when the load-counter variable is known. Then, the values of the load-counter variable $l(\sigma_{\text{exp}}^*)$ corresponding to the *in situ* loading can be determined using the experimentally measured load-counter metric values σ_{exp}^* by the following inverse function:

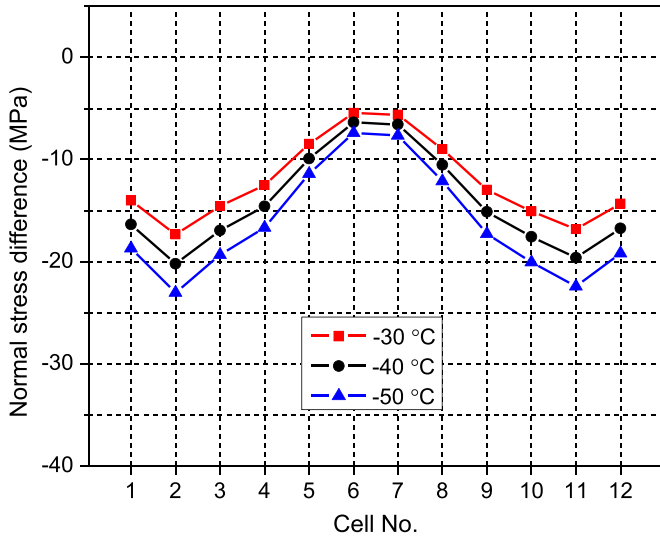
$$l(\sigma_{\text{exp}}^*) = L^{-1}(\sigma_{\text{exp}}^*). \quad (4)$$

C. Implementation of Load-Counter for Passive Thermal Cycling

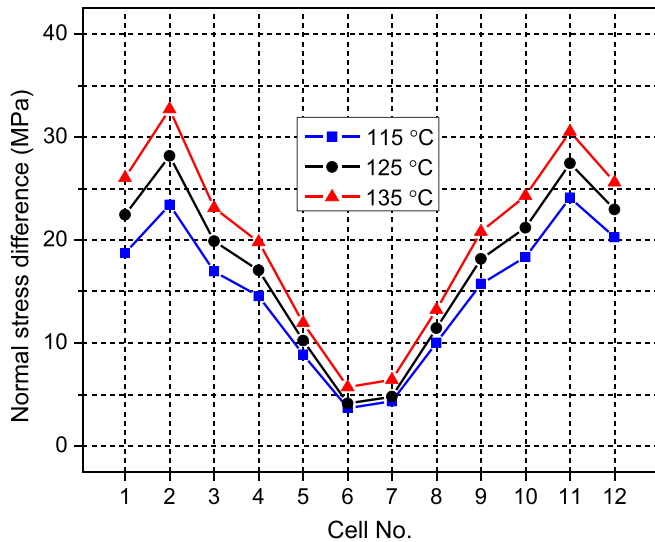
Five molded ECUs were placed in an environmental chamber and subjected to a passive thermal cycle of $-40\text{ }^{\circ}\text{C}$ to $125\text{ }^{\circ}\text{C}$. The stress data for each ECU were recorded during the test, from which the load-counter metric was calculated. The load-counter metric during the first five cycles is shown in Fig. 17. The large variations among the units are evident.

A relative large environmental chamber was used to accommodate all five ECUs as well as a large number of cables connecting the sensors to DAQ units. The temperature variation within the chamber was inevitable, which caused the large variations of stress signals among the units. Thus, the temperature variation was regarded as the load-counter variable in this paper.

In order to establish the load-counter function, the effect of the temperature variation on the stress-sensing cells was examined using the calibrated model. The representative stress signals around $-40\text{ }^{\circ}\text{C}$ and $125\text{ }^{\circ}\text{C}$ are plotted in Fig. 18(a) and (b). The results clearly show that the stress signals from all 12 cells change consistently with the temperature variations. The load-counter metric was, then, calculated around $-40\text{ }^{\circ}\text{C}$ and $125\text{ }^{\circ}\text{C}$ with a constant interval of $5\text{ }^{\circ}\text{C}$. The results are shown in Fig. 19. A linear function and a quadratic function were used to fit the results for the low- and high-temperature regions, respectively. The load-counter



(a)



(b)

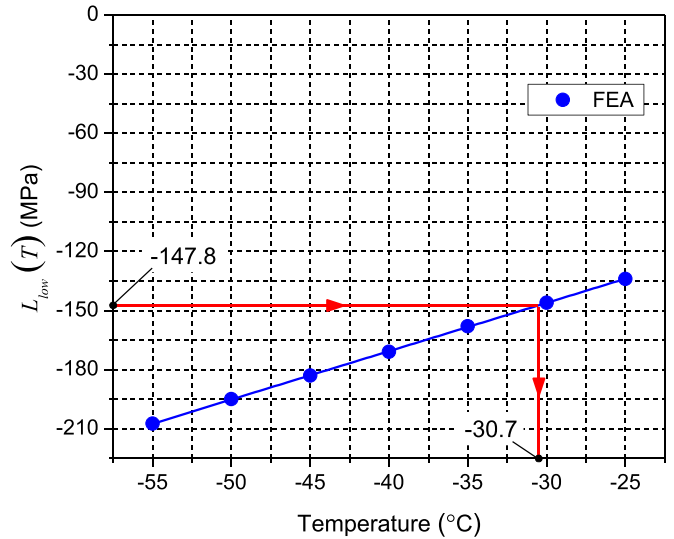
Fig. 18. Stress signals around (a) $-40\text{ }^{\circ}\text{C}$ and (b) $125\text{ }^{\circ}\text{C}$.

functions for two temperature regions are expressed as

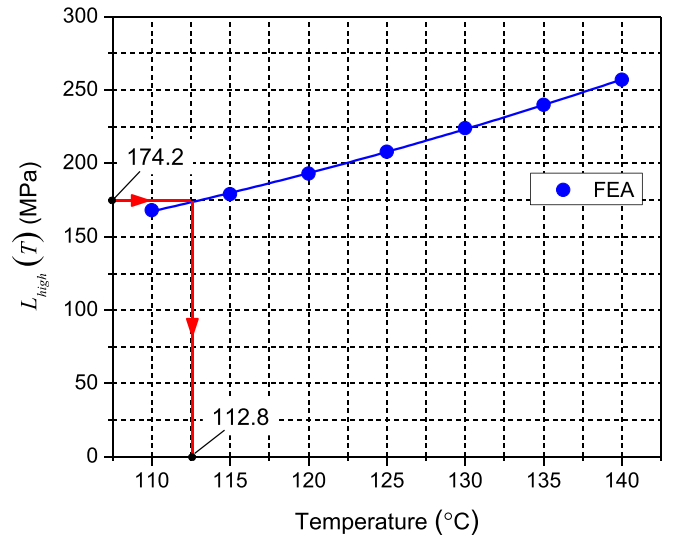
$$\begin{aligned} \sigma_{\text{low}}^*(T) &= L_{\text{low}}(T) = 2.45T - 72.57 \\ &\text{for } -55\text{ }^{\circ}\text{C} < T < -25\text{ }^{\circ}\text{C} \\ \sigma_{\text{high}}^*(T) &= L_{\text{high}}(T) = 0.02T^2 - 2T + 145.36 \\ &\text{for } 110\text{ }^{\circ}\text{C} < T < 140\text{ }^{\circ}\text{C}. \end{aligned} \quad (5)$$

Then, the *in situ* loading can be determined from the measured load-counter metric values using the above functions.

Fig. 19 illustrates how the *in situ* loading (T) was determined from the measured load-counter metric (σ_{exp}^*) using the value of Sample 3. At the low peak, the σ_{exp}^* value of Sample 3 was -147.8 MPa , which yielded the temperature loading of $-30.7\text{ }^{\circ}\text{C}$. The corresponding values at the high peak were 174.2 MPa and $112.8\text{ }^{\circ}\text{C}$, respectively. The values of the load-counter metric measured from the units during the first thermal cycle, and the corresponding *in situ* loadings (T)



(a)



(b)

Fig. 19. Relationship between the load-counter metric and temperature at (a) low- and (b) high-temperature regions.

TABLE III
In Situ THERMAL LOADING DURING DWELL PERIODS

	Sample 1	Sample 2	Sample 3	Sample 4	Sample 5
At nominal $-40\text{ }^{\circ}\text{C}$ dwell period					
σ_{exp}^* [MPa]	-192.8	-167.7	-147.8	-192.9	-176.2
T ($^{\circ}\text{C}$)	-49.0	-38.8	-30.7	-49.1	-42.3
At nominal $125\text{ }^{\circ}\text{C}$ dwell period					
σ_{exp}^* [MPa]	231.5	181.8	174.2	220.9	212.1
T ($^{\circ}\text{C}$)	132.5	115.8	112.8	129.1	126.4

are summarized in Table III. The *in situ* loading variation of the low-temperature ($-40\text{ }^{\circ}\text{C}$) region is $18.4\text{ }^{\circ}\text{C}$, while the variation at the high-temperature ($125\text{ }^{\circ}\text{C}$) region is $19.7\text{ }^{\circ}\text{C}$.

The calibrated model used the *in situ* loadings to calculate the resultant forces acting on the interface between an aluminum wire bond and metal pad [see Fig. 14(b)]. The results are shown in Fig. 20(a) and (b) for the normal and shear forces, respectively. The difference of the forces at the wire

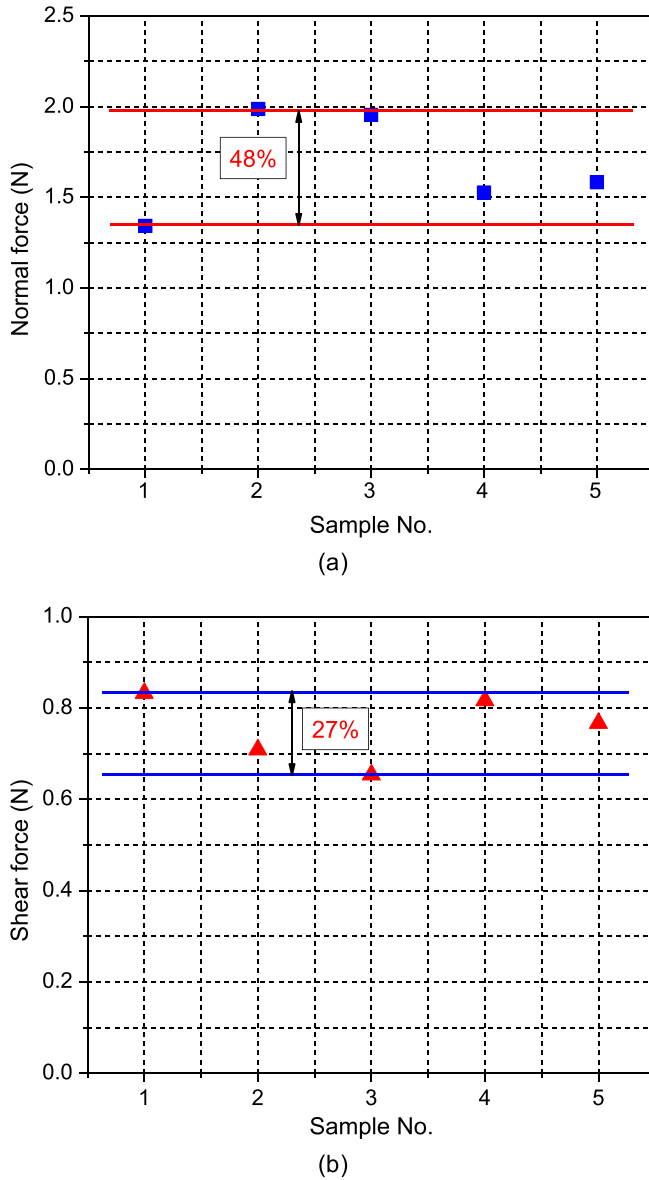


Fig. 20. Resultant forces acting on the Al wire bond interface. (a) Normal force. (b) Shear force.

bond interface among five units caused by the *in situ* loading variation is as large as 48% for the normal force and 27% for the shear force.

Large variations of the stress loading on the wire bond interface are evident, and thus different lifetimes are expected. The fatigue models can be utilized to predict the lifetime of wire bonds inside the DPAK under the thermal cyclic loading [21], [23]–[26]. Then, failure prognostics of the ECU product under the field condition can be performed using the damage index, such as the stress or strain range and the strain energy density, determined by the verified FEA model.

V. CONCLUSION

A model/sensor hybrid approach was developed and implemented for failure prognostics of an automotive ECU. In the approach, the predictability of a 3-D finite-element model for

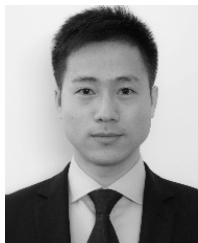
the complex molded ECU was calibrated and subsequently verified by moiré interferometry. The effective *in situ* loading history was obtained using the data obtained from a stress sensor in conjunction with a load-count metric that converted the stress signals into *in situ* temperature excursions. The calibrated model used the *in situ* loadings to calculate the resultant forces acting on the interface between an aluminum wire bond and metal pad. The significant differences were observed.

Although a relatively simple *in situ* thermal loading was used to illustrate the concept of the load-counter in this paper, the *in situ* stress sensor data could be converted for a wide range of *in situ* loadings. Then, the proposed hybrid approach can be used effectively to determine the actual loading variations of ECUs in the field, which can be subsequently utilized for failure prognostics.

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